



1764

Docket No. 2000-022R1  
PATENT

CERTIFICATE OF MAILING

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BY: Annie Wong  
Annie Wong

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:	Bergh et al.	Group Art Unit:	1764
Serial No.:	09/801, 390		
Filed:	March 7, 2001		
For:	Parallel Flow Process Optimization Reactor	Examiner:	Unknown

Assistant Commissioner for Patents  
Washington, D.C. 20231

TRANSMITTAL LETTER

Sir:

Transmitted herewith (check all that apply):

- |  |  |
|--|--|
| <input type="checkbox"/> Preliminary Amendment             | <input checked="" type="checkbox"/> Information Disclosure Statement |
| <input type="checkbox"/> Response/Amendment                | <input type="checkbox"/> Petition Under 37 CFR 1.97(d)(2)            |
| <input type="checkbox"/> Response/Amendment After Final    | <input type="checkbox"/> Formal Drawings                             |
| <input type="checkbox"/> Supplemental Amendment            | <input type="checkbox"/> Declaration Under 37 CFR 1.131              |
| <input type="checkbox"/> Affidavits/Declarations           | <input type="checkbox"/> Declaration Under 37 CFR 1.132              |
| <input type="checkbox"/> Declaration and Power of Attorney | <input type="checkbox"/> Terminal Disclaimer                         |
| <input type="checkbox"/> Supplemental Declaration          | <input type="checkbox"/> Small Entity Statement                      |
| <input type="checkbox"/> Associate Power of Attorney       | <input type="checkbox"/> Request for Refund                          |
| <input type="checkbox"/> Change of Correspondence Address  | <input type="checkbox"/> Appeal                                      |
| <input type="checkbox"/> Associate Power of Attorney       | <input type="checkbox"/> Petition to Correct "Date-In" Date          |
| <input type="checkbox"/> Response to Missing Parts         | <input type="checkbox"/> Request to Correct Filing Receipt           |

to be filed in the above-identified patent application.

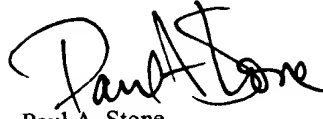
☒ No fee is required.

☒ The Commissioner is hereby authorized to charge payment of any additional filing fees required under 37 C.F.R. § 1.16, in connection with the paper(s) transmitted herewith, or credit any overpayment of same, to Deposit Account No. 50-0496.

A duplicate copy of this Transmittal Letter is transmitted herewith.

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Respectfully submitted,

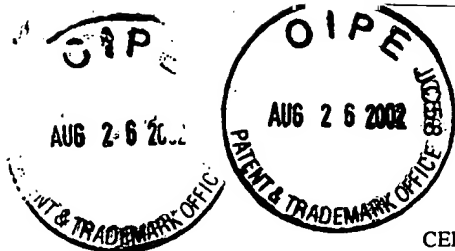


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Date: Aug. 14, 2002

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Docket No. 2000-022R1  
Patent

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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of: Bergh et al.  
Serial No.: 09/801,390  
Filed: 3/7/01  
For: Parallel Flow Process Optimization  
Reactor

Group Art Unit: 1764

Examiner: Unknown

Assistant Commissioner for Patents  
Washington, D.C. 20231

INFORMATION DISCLOSURE STATEMENT

Sir:

Applicants submit herewith patents, publications and other information of which they are aware, which they believe an examiner may consider to be material to the patentability of the claims of this application, and in respect of which there may be a duty to disclose in accordance with 37 C.F.R. § 1.56.

While this Information Disclosure Statement may contain "material" information pursuant to 37 C.F.R. § 1.56, it is not intended to constitute an admission that any patent, publication or other information referred to herein is either "material" or "prior art" to the invention disclosed and claimed in the above-referenced application unless specifically designated as such. Applicants specifically reserve the right, where appropriate, to avoid or antedate any such reference by the appropriate arguments or showings under 37 C.F.R. § 1.131 and § 1.608, or any other appropriate means.

A completed PTO Form 1449 listing each reference is submitted herewith, and it is respectfully requested that an Examiner initialed copy of the PTO Form 1449 be returned to the undersigned. A copy of each reference therein listed accompanies this Information Disclosure Statement.

This Information Disclosure Statement is being filed within three months of the filing or entry of the national stage of this application, or before the mailing of a first Office Action on the merits, whichever is later. No fee is required under 37 C.F.R. § 1.97(b). However, in the event that more than 90 days from filing have elapsed and a first Office Action on the merits has been mailed, the Commissioner is hereby authorized to charge the fee required under 37 C.F.R. 1.17(p) to Deposit Account Number 50-0496.

The Examiner is hereby requested to consider these references and other information and make them of record in the above-referenced application. Applicants respectfully submit that the claims of this application are patentable over the above-cited references and information. Examination and allowance of this application at an early date are requested.

Respectfully submitted,

Date:

Aug. 14, 2002

By:

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**INFORMATION DISCLOSURE  
CITATION**

PTO-1449

ATTORNEY'S DOCKET NO.:

2000-022R1

APPLICATION NO.:

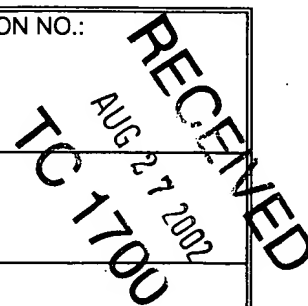
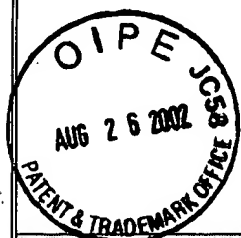
09/801,390


APPLICANT:

Bergh et al.

FILING DATE:  
3/7/2001GROUP:  
1764
**US PATENT DOCUMENTS**

EXAMINER'S INITIALS	PATENT NO.	DATE	NAME	CLASS	SUBCLASS	FILING DATE
	3,431,077	3/04/69	Danforth	23	253	7/18/66
	3,536,452	10/27/70	Norton et al.	23	259	12/10/62
	4,099,923	7/11/78	Milberger	23	254 R	1/17/77
	4,705,669	11/10/87	Tsuji et al.	422	93	8/27/86
	4,869,282	9/26/89	Sittler et al.	137	15	12/09/88
	4,996,387	2/26/91	Gerhold et al.	585	654	7/20/89
	5,089,232	2/18/92	May	422	83	1/24/90
	5,252,294	10/12/93	Kroy et al.	422	102	2/03/92
	5,304,354	4/19/94	Finley et al.	422	196	11/30/92
	5,324,483	6/28/94	Cody et al.	422	131	2/02/93
	5,417,938	5/23/95	Shelden et al.	422	196	
	5,534,328	7/09/96	Ashmead et al.	428	166	12/02/93
	5,580,523	12/03/96	Bard	422	50	4/01/94
	5,589,136	12/31/96	Northrup et al.	422	102	6/20/95
	5,593,642	1/14/97	DeWitt et al.	422	131	6/05/95
	5,595,712	1/21/97	Harbster et al.	422	129	7/25/94
	5,603,351	2/18/97	Cherukuri et al.	137	597	6/07/95
	5,611,214	3/18/97	Wegeng et al.	62	498	7/29/94
	5,639,423	6/17/97	Northrup et al.	122	50	8/31/92
	5,658,537	8/19/97	Dugan	422	191	7/18/95
	5,690,763	11/25/97	Ashmead et al.	156	60	6/06/95
	5,750,906	5/12/98	Parker et al.	73	863.73	10/29/96
	5,776,359	7/07/98	Schultz et al.	252	62.51	5/08/95
	5,780,748	7/14/98	Barth	73	861.47	1/29/97
	5,811,062	9/22/98	Wegeng et al.	422	129	2/23/96
	5,833,926	11/10/98	Wurzel et al.	422	81	10/24/95
	5,842,787	12/01/98	Kopf-Sill et al.	366	340	10/9/97
	5,843,385	12/01/98	Dugan	422	191	4/02/97
	5,863,801	1/26/99	Southgate et al.	436	63	6/14/96



<b>INFORMATION DISCLOSURE CITATION</b>   PTO-1449	ATTORNEY'S DOCKET NO.: 2000-022R1	APPLICATION NO.: 09/801,390
	APPLICANT: Bergh et al.	
	FILING DATE: 3/7/2001	GROUP: 1764

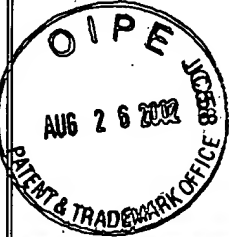
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### US PATENT DOCUMENTS

EXAMINER'S INITIALS	PATENT NO.	DATE	NAME	CLASS	SUBCLASS	FILING DATE
	5,865,417	2/02/99	Harris et al.	251	11	9/27/96
	5,869,004	2/09/99	Parce et al.	422	100	6/09/97
	5,872,010	2/16/99	Karger et al.	436	173	7/03/96
	5,922,591	7/13/99	Anderson et al.	435	287.2	6/27/96
	5,927,325	7/27/99	Bensaoula et al.	137	599	10/25/96
	5,959,297	9/28/99	Weinberg et al.	250	288	10/8/97
	5,985,356	11/16/99	Schultz et al.	427	8	10/18/94
	6,004,617	12/21/99	Schultz et al.	427	8	6/07/95
	6,030,917	2/29/00	Weinberg et al.	502	104	7/22/97
	6,033,544	3/07/00	Demers et al.	204	450	11/7/96
	6,063,633	5/16/00	Willson	436	37	6/17/96
	6,087,181	7/11/00	Cong	436	37	3/16/98
	6,149,882	11/21/00	Guan et al.	422	211	6/09/98
	6,175,409	1/16/01	Nielsen et al.	356	337	4/02/99
	US-20020014106	2/07/02	Srinivasan et al.			3/07/01
	US-20020042140	4/11/02	Hagemeyer et al.			7/09/01
	US-20020045265	4/18/02	Bergh et al.			3/08/01
	US-20020048536	4/25/02	Bergh et al.			3/07/01

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	967,261	3/15/62	United Kingdom	B01J			
	DD 234 941 A1	4/16/86	Germany	G01N	31/10		x
	DE 27 14 939 B2	11/29/79	Germany	G01N	31/10		x
	DE 196 32 779 A1	2/19/98	Germany	G01N	35/00	x	
	DE 198 05 719 A1	8/19/99	Germany	B01J	35/04	x	
	DE 198 06 848 A1	8/19/99	Germany	B01J	35/02	x	
	DE 198 09 477 A1	9/16/99	Germany	G01N	31/10	x	
	DE 198 55 894 A1	6/08/00	Germany	B01J	35/04		x

<b>INFORMATION DISCLOSURE CITATION</b>  PTO-1449  	ATTORNEY'S DOCKET NO.: 2000-022R1	APPLICATION NO.: 09/801,390
	APPLICANT: Bergh et al.	
	FILING DATE: 3/7/2001	GROUP: 1764

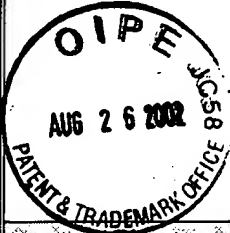
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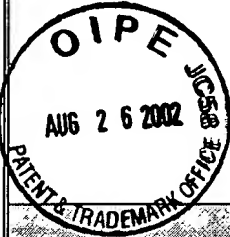
EXAMINER'S INITIALS	PATENT NO.	DATE	COUNTRY	CLASS	SUB CLASS	TRANSLATION YES NO	
	EP 0 796 654 A2	9/24/97	EPO	B01J	19/00		
	EP 0 886 143 A1	12/23/98	EPO	G01N	33/68		
	WO 96/15576	5/23/96	PCT	H02K	44/02		
	WO 97/32208	9/04/97	PCT	G01N	31/10		
	WO 98/00231	1/08/98	PCT	B01J	19/00		
	WO 98/03521	1/29/98	PCT	C07F	19/00		
	WO 98/07026	2/19/98	PCT	G01N	31/10	x	
	WO 98/13137	4/02/98	PCT	B01J	19/00		
	WO 98/13605	4/02/98	PCT	F15C	5/00		
	WO 98/16949	4/23/98	PCT	H01J	49/40		x
	WO 98/22811	5/28/98	PCT	G01N	27/26		
	WO 98/53236	11/26/98	PCT	F16K	31/126		
	WO 98/55852	12/10/98	PCT	G01N	27/26		
	WO 98/56505	12/17/98	PCT	B01L	3/00		
	WO 99/41005	8/19/99	PCT	B01J	19/00	x	
	WO 99/64160	12/16/99	PCT	B01L	3/02		
	WO 00/09255	2/24/00	PCT	B01J	19/00		
	WO 00/14529	3/16/00	PCT	G01N	31/02		
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<b>INFORMATION DISCLOSURE CITATION</b>   PTO-1449	ATTORNEY'S DOCKET NO.:  2000-022R1	APPLICATION NO.:  09/801,390
	APPLICANT:  Bergh et al.	
	FILING DATE: 3/7/2001	GROUP: 1764
<b>OTHER DOCUMENTS (including Author, Title, Date, Pertinent Pages etc.)</b>		
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<b>OTHER DOCUMENTS (including Author, Title, Date, Pertinent Pages etc.)</b>		
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	Srinivasan, R. et al., "Micromachined Reactors for Catalytic Partial Oxidation Reactions", <i>AIChE Journal</i> , 1997, Vol. 43, No. 11, pp. 3059-3069	
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EXAMINER:	DATE CONSIDERED:	

Examiner: Initial if reference considered, whether or not citation is in conformance with M.P.E.P. 609; draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.